ABSTRACT OF THE DISCLOSURE

Provided herein is an apparatus suitable for scrubbing either acidic or alkaline impurities from gas streams, wherein the gas streams to be scrubbed exist at a pressure which is only slightly higher than ambient pressure.

An apparatus according to a preferred form of the invention exists substantially is the shape of a rectangular or cubic solid, having an inlet pipe which is directed to an inner chamber having a wall portion which functions as a manifold, comprising a plurality of gas conduction tubes in fluid contact with the inner chamber, and into which tubes the gas to be scrubbed enters. The gas to be scrubbed passes through holes in the walls of the gas conduction tubes and contacts a liquid absorbent substance present in the interior confines of the apparatus, which liquid is capable of reacting with one or more impurities in the gas stream, thus eliminating the impurities from the gas stream. The gas stream so treated emerges the apparatus through a gas outlet provision.